



Optical In-Process Measurement Systems

Guest Editor:

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Deadline for manuscript
submissions:

closed (1 January 2022)

Message from the Guest Editor

We are interested in articles that investigate in-process measurements by means of optical principles (VIS, IR, UV). Potential topics include, but are not limited to, the following:

- innovative measurement principles using visible, infrared, or ultraviolet light;
- model-based measurement approaches and/or data fusion that enable new measurands;
- scaling of the measurement range from the lab to the app;
- knowledge extraction from less-reproducible in-process measurement conditions;
- fast measurements using scanning and multiplexing techniques;
- measurement systems with adaptive components;
- investigation and correction of cross-sensitivities;
- limits of measurability by studying the minimal achievable measurement uncertainty;
- novel findings about the investigated process due to in-process measurements;
- application case studies; and
- applicability of a single measurement principle for different in-process applications and vice versa.

Original work highlighting the latest research and technical development is encouraged, but review papers and comparative studies are also welcome.





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Editor-in-Chief

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Message from the Editor-in-Chief

As the world of science becomes ever more specialized, researchers may lose themselves in the deep forest of the ever increasing number of subfields being created. This open access journal Applied Sciences has been started to link these subfields, so researchers can cut through the forest and see the surrounding, or quite distant fields and subfields to help develop his/her own research even further with the aid of this multi-dimensional network.

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